

SECTION G — PHYSICS

G01 MEASURING; TESTING

G01Q SCANNING-PROBE TECHNIQUES OR APPARATUS; APPLICATIONS OF SCANNING-PROBE TECHNIQUES, e.g. SCANNING-PROBE MICROSCOPY [SPM] [2010.01]

Note(s) [2010.01]

In this subclass, the first place priority rule is applied, i.e. at each hierarchical level, in the absence of an indication to the contrary, classification is made in the first appropriate place.

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| <p>10/00 Scanning or positioning arrangements, i.e. arrangements for actively controlling the movement or position of the probe [2010.01]</p> <p>10/02 • Coarse scanning or positioning [2010.01]</p> <p>10/04 • Fine scanning or positioning [2010.01]</p> <p>10/06 • • Circuits or algorithms therefor [2010.01]</p> <p>20/00 Monitoring the movement or position of the probe [2010.01]</p> <p>20/02 • by optical means [2010.01]</p> <p>20/04 • Self-detecting probes, i.e. wherein the probe itself generates a signal representative of its position, e.g. piezo-electric gauge [2010.01]</p> <p>30/00 Auxiliary means serving to assist or improve the scanning probe techniques or apparatus, e.g. display or data processing devices [2010.01]</p> <p>30/02 • Non-SPM analysing devices, e.g. SEM [Scanning Electron Microscope], spectrometer or optical microscope [2010.01]</p> <p>30/04 • Display or data processing devices [2010.01]</p> <p>30/06 • • for error compensation [2010.01]</p> <p>30/08 • Means for establishing or regulating a desired environmental condition within a sample chamber [2010.01]</p> <p>30/10 • • Thermal environment [2010.01]</p> <p>30/12 • • Fluid environment [2010.01]</p> <p>30/14 • • • Liquid environment [2010.01]</p> <p>30/16 • • Vacuum environment [2010.01]</p> <p>30/18 • Means for protecting or isolating the interior of a sample chamber from external environmental conditions or influences, e.g. vibrations or electromagnetic fields [2010.01]</p> <p>30/20 • Sample handling devices or methods [2010.01]</p> <p>40/00 Calibration, e.g. of probes [2010.01]</p> <p>40/02 • Calibration standards or methods of fabrication thereof [2010.01]</p> <p>60/00 Particular types of SPM [Scanning-Probe Microscopy] or apparatus therefor; Essential components thereof [2010.01]</p> <p>60/02 • Multiple-type SPM, i.e. involving two or more SPM techniques [2010.01]</p> <p>60/04 • • STM [Scanning Tunnelling Microscopy] combined with AFM [Atomic Force Microscopy] [2010.01]</p> | <p>60/06 • • SNOM [Scanning Near-field Optical Microscopy] combined with AFM [Atomic Force Microscopy] [2010.01]</p> <p>60/08 • • MFM [Magnetic Force Microscopy] combined with AFM [Atomic Force Microscopy] [2010.01]</p> <p>60/10 • STM [Scanning Tunnelling Microscopy] or apparatus therefor, e.g. STM probes [2010.01]</p> <p>60/12 • • STS [Scanning Tunnelling Spectroscopy] [2010.01]</p> <p>60/14 • • STP [Scanning Tunnelling Potentiometry] [2010.01]</p> <p>60/16 • • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]</p> <p>60/18 • SNOM [Scanning Near-Field Optical Microscopy] or apparatus therefor, e.g. SNOM probes [2010.01]</p> <p>60/20 • • Fluorescence [2010.01]</p> <p>60/22 • • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]</p> <p>60/24 • AFM [Atomic Force Microscopy] or apparatus therefor, e.g. AFM probes [2010.01]</p> <p>60/26 • • Friction force microscopy [2010.01]</p> <p>60/28 • • Adhesion force microscopy [2010.01]</p> <p>60/30 • • Scanning potential microscopy [2010.01]</p> <p>60/32 • • AC mode [2010.01]</p> <p>60/34 • • • Tapping mode [2010.01]</p> <p>60/36 • • DC mode [2010.01]</p> <p>60/38 • • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]</p> <p>60/40 • • • Conductive probes [2010.01]</p> <p>60/42 • • • Functionalisation [2010.01]</p> <p>60/44 • SICM [Scanning Ion-Conductance Microscopy] or apparatus therefor, e.g. SICM probes [2010.01]</p> <p>60/46 • SCM [Scanning Capacitance Microscopy] or apparatus therefor, e.g. SCM probes [2010.01]</p> <p>60/48 • • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]</p> <p>60/50 • MFM [Magnetic Force Microscopy] or apparatus therefor, e.g. MFM probes [2010.01]</p> <p>60/52 • • Resonance [2010.01]</p> <p>60/54 • • Probes, their manufacture or their related instrumentation, e.g. holders [2010.01]</p> <p>60/56 • • • Probes with magnetic coating [2010.01]</p> <p>60/58 • SThM [Scanning Thermal Microscopy] or apparatus therefor, e.g. SThM probes [2010.01]</p> <p>60/60 • SECM [Scanning Electro-Chemical Microscopy] or apparatus therefor, e.g. SECM probes [2010.01]</p> |
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G01Q

70/00 General aspects of SPM probes, their manufacture or their related instrumentation, insofar as they are not specially adapted to a single SPM technique covered by group G01Q 60/00 [2010.01]

70/02 • Probe holders [2010.01]

70/04 • • with compensation for temperature or vibration induced errors [2010.01]

70/06 • Probe tip arrays [2010.01]

70/08 • Probe characteristics [2010.01]

70/10 • • Shape or taper [2010.01]

70/12 • • • Nanotube tips [2010.01]

70/14 • • Particular materials [2010.01]

70/16 • Probe manufacture [2010.01]

70/18 • • Functionalisation [2010.01]

80/00 Applications, other than SPM, of scanning-probe techniques (manufacture or treatment of microstructures B81C; manufacture or treatment of nanostructures B82B 3/00; recording or reproducing information using near-field interaction G11B 9/12, G11B 11/24 or G11B 13/08) [2010.01]

90/00 Scanning-probe techniques or apparatus not otherwise provided for [2010.01]